

Comparison of EUV and electron reactivity for metal oxalate photoresists

Steven Grzeskowiak,^a Amrit Narasimhan,^a Michael Murphy,^a Jodi Hotalen,^a
Christian Ackerman,^a Jake Kaminsky,^a Lee Napolitano,^b Daniel A. Freedman,^b
Robert L. Brainard,^a and Greg Denbeaux^a

(a) SUNY Polytechnic Institute – Colleges of Nanoscale Science and Engineering
257 Fuller Rd. Albany, NY, USA 12203

(b) State University of New York at New Paltz, 1 Hawk Drive New Paltz, NY 12561

IEUVI Resist Technical Working Group
February 26th, 2017

Monday 2:20-2:40 pm, “Reactivity of Metal Oxalate EUV Resists as a Function of the Central Metal,”
Presentation by Steven Grzeskowiak (10146-4)

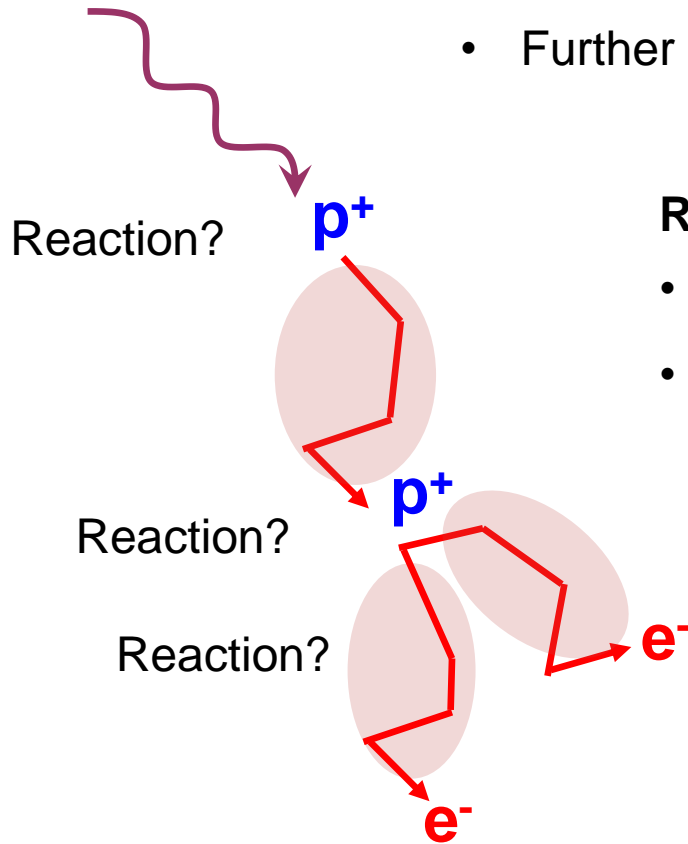
EUV Lithography

EUV Lithography

- Photons liberate electrons in the resist and possibly cause chemistry to occur in the process
- Further Chemistry due to electron-resist interactions

92 eV (13.5 nm)

$h\nu$



Resist chemistry can be improved by:

- Increasing the number of photons absorbed
- Efficient reactivity of secondary electrons

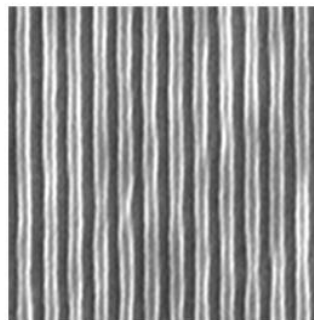
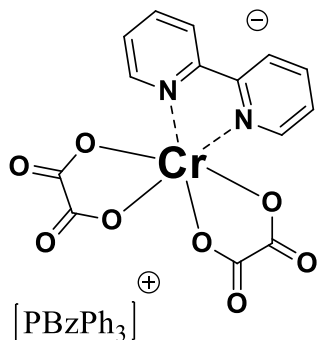
References

- ¹T. Kozawa and S. Tagawa, *Jpn. J. Appl. Phys.*, **49** (3) (2010) 030001.
- ²A. Narasimhan, S. Grzeskowiak, et al., *Proc. SPIE*, **9779** (2016) 97790F.
- ³J. Torok, et al., *J. Photopolym. Sci. and Technol.*, **26** (5) (2013) 625–634.
- ⁴P. de Schepper, et al., *Proc. SPIE*, **9425** (2015) 942507.
- ⁵T. H. Fedynyshyn, et al., *Proc. SPIE*, **5039** (2003) 310.

Number of Electrons?
2-4 e⁻/photon¹⁻⁵

Comparison of Metal Centers Previous Work

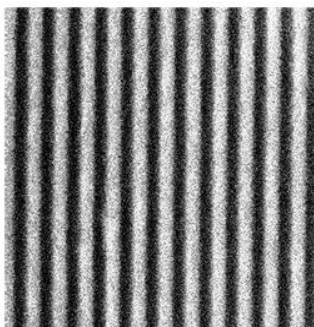
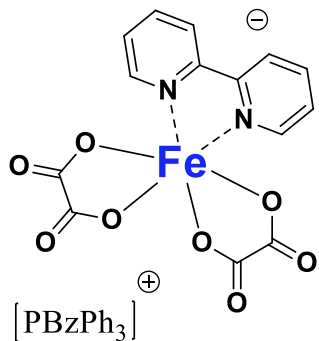
NP4: Cr



$$E_{\text{size}} = 70 \text{ mJ/cm}^2$$

- Number of d electrons = 3
- Oxidation State = (III)
- *Calculated EUV abs. = $5.8 \mu\text{m}^{-1}$

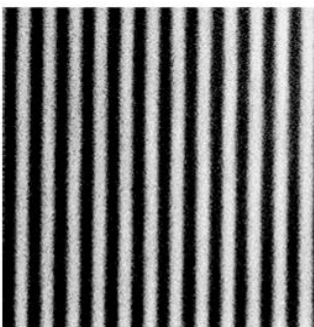
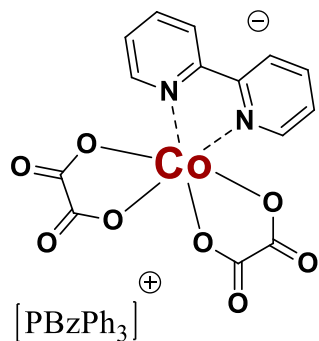
NP3: Fe



$$E_{\text{size}} = 48 \text{ mJ/cm}^2$$

- Number of d electrons = 5
- Oxidation State = (III)
- *Calculated EUV abs. = $6.0 \mu\text{m}^{-1}$

NP1: Co



$$E_{\text{size}} = 27 \text{ mJ/cm}^2$$

- Number of d electrons = 6
- Oxidation State = (III)
- *Calculated EUV abs. = $6.1 \mu\text{m}^{-1}$

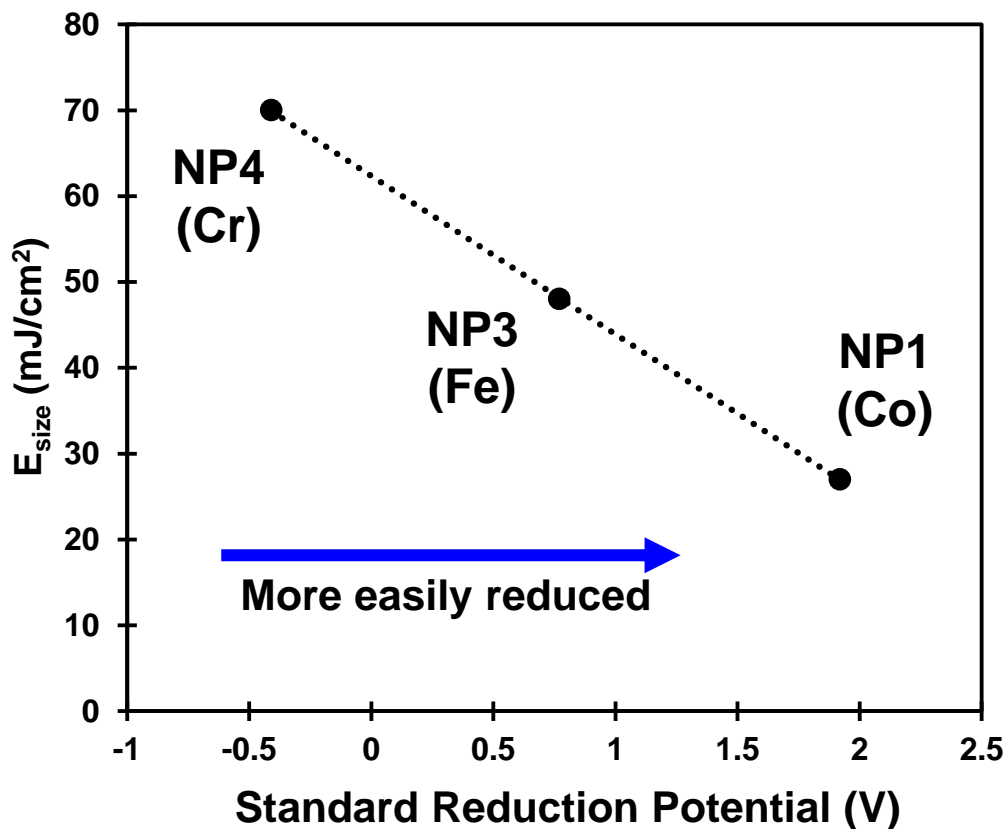
Improved Sensitivity

35 nm h/p lines

*Calculated values are based on CXRO absorption using an assumed film density of 1.5 g/cm^3

⁷M. Marnell, et al., "A Molecular Inorganic Approach to EUV Photoresists", presented at SPIE advanced lithography conference, (February 2014), San Jose, CA.

E_{size} vs. Metal Center Redox Potential



Literature Values⁸⁻¹²

| Metal Reduction from (III to II) | Standard Redox Potential (V) |
|--|------------------------------|
| $\text{Co}^{3+} + e^- \rightleftharpoons \text{Co}^{2+}$ | +1.92 |
| $\text{Fe}^{3+} + e^- \rightleftharpoons \text{Fe}^{2+}$ | +0.77 |
| $\text{Cr}^{3+} + e^- \rightleftharpoons \text{Cr}^{2+}$ | -0.41 |

⁸D. R. Lide (Editor-in-Chief), "*CRC Handbook of Chemistry and Physics, 83rd edition*," CRC Press, (2002-2003).

⁹Nobuyuki Tanaka, and Michio Nanjo, "*The Thermal Decomposition of Metal Oxalato Complexes*," *Bull. Chem. Soc. Jpn.* **40** (2) (1967) 330-333.

¹⁰A. J. Bard, R. Parsons, and J. Joseph, "*Standard potentials in aqueous solution*," CRC Press **6**, (1985).

¹¹G. Milazzo and S. Caroli, "*Tables of Standard Electrode Potentials*," *Analytica Chimica Acta* **105** (1979) 459.

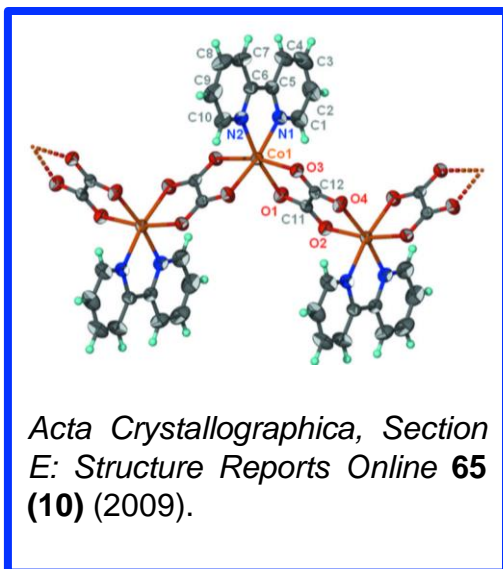
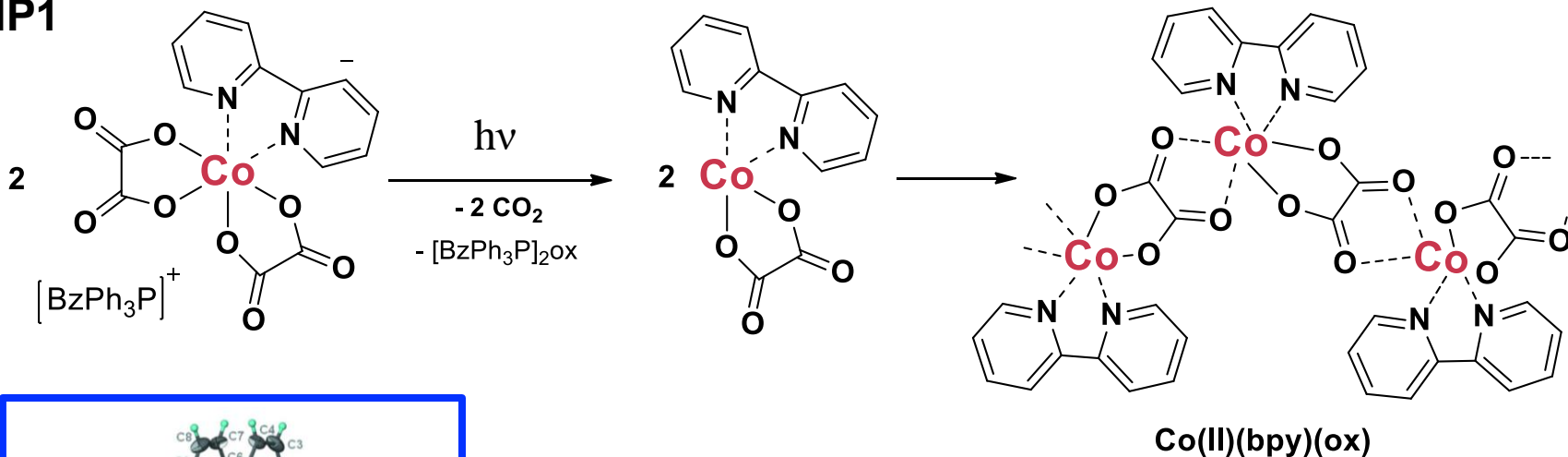
¹²D. C. Harris, "*Quantitative chemical analysis, 8th edition*," Macmillan (2010).

- There appears to be a correlation between the reducibility of the metal and E_{size} .
- **Hypothesis:** There may be a correlation between reducibility of the metal and CO_2 outgassing based upon the photo-mechanism.

Molecular Organometallic Resists for EUV (MORE): Cobalt Compound (NP1)

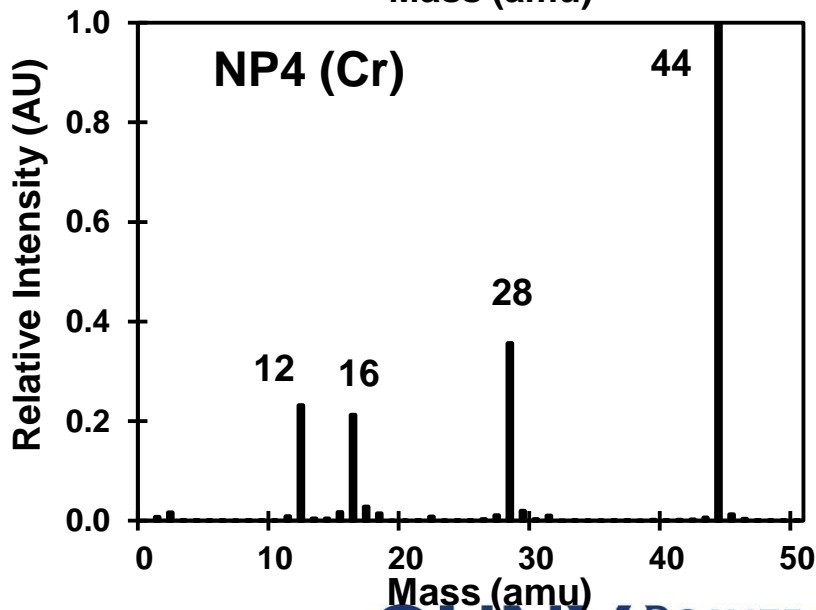
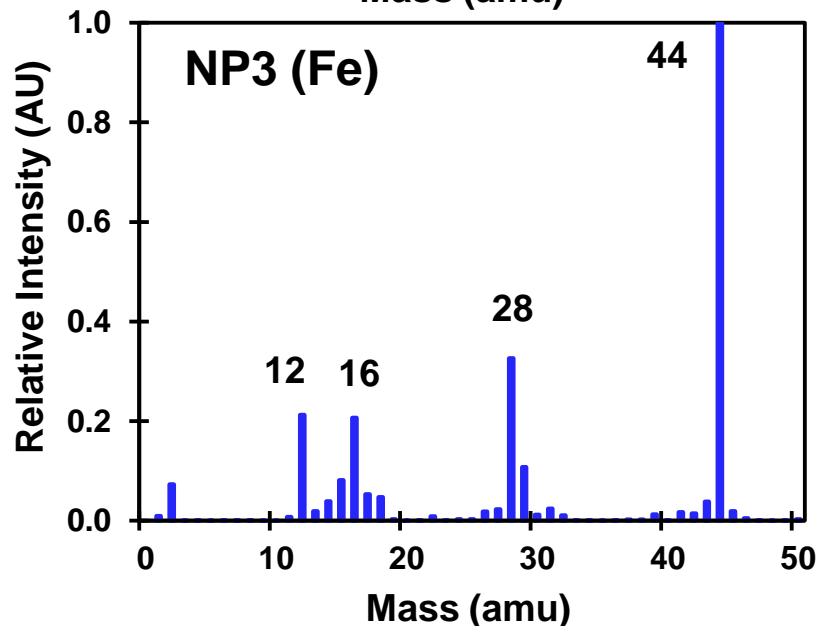
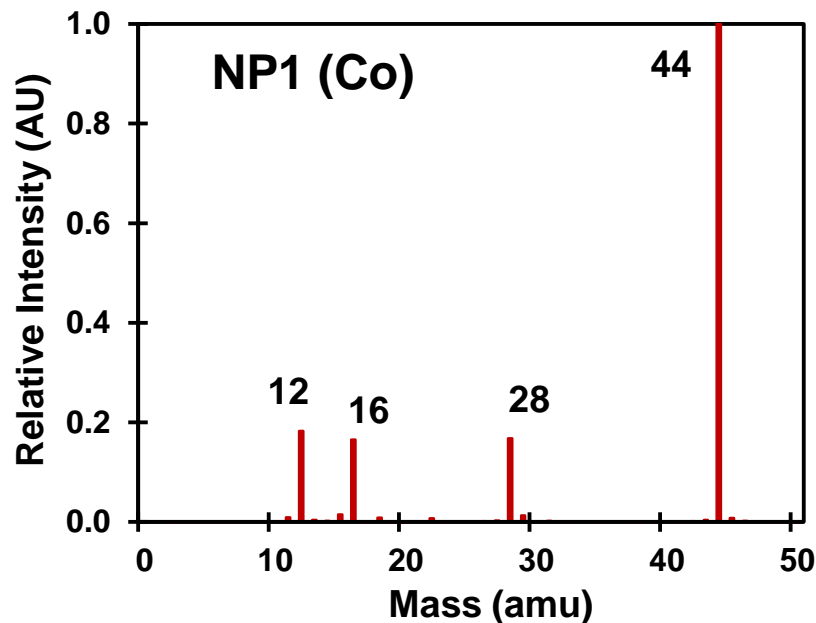
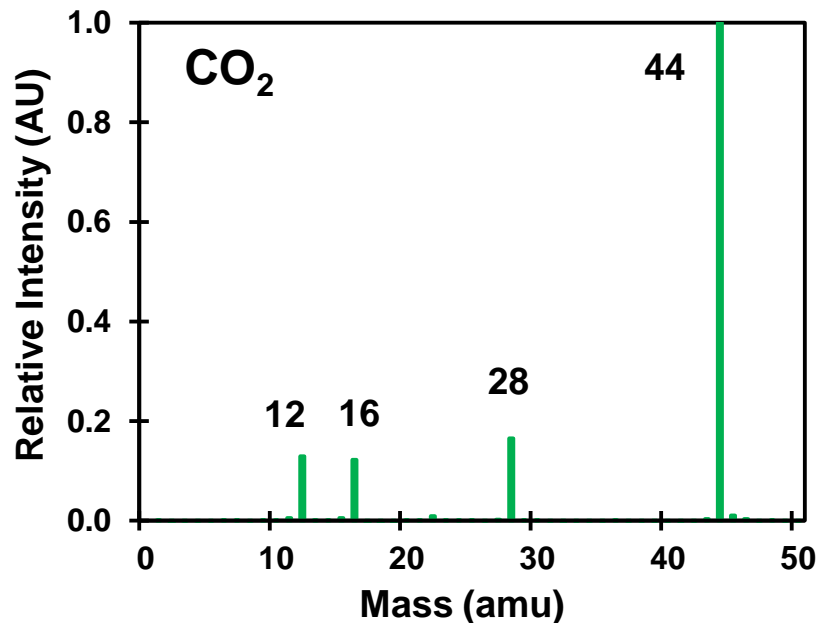
Current understanding of photo-mechanism:

NP1

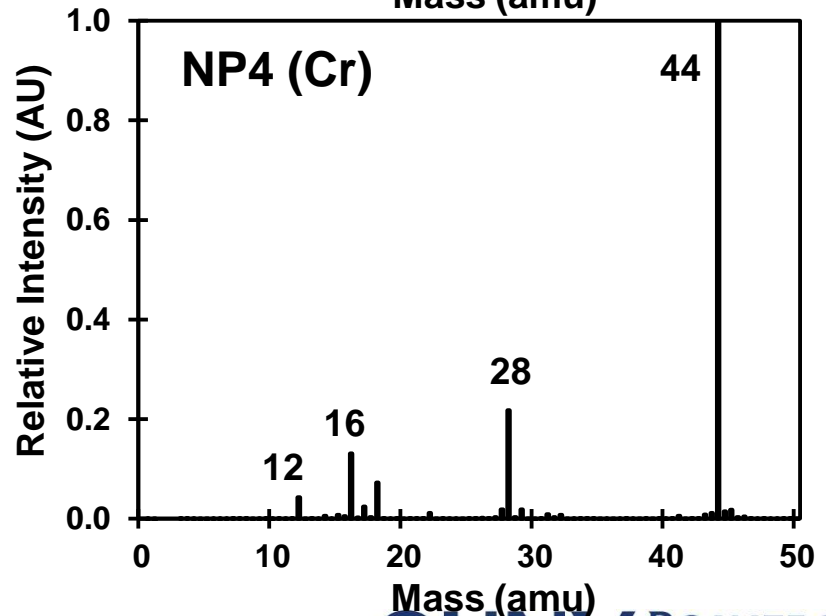
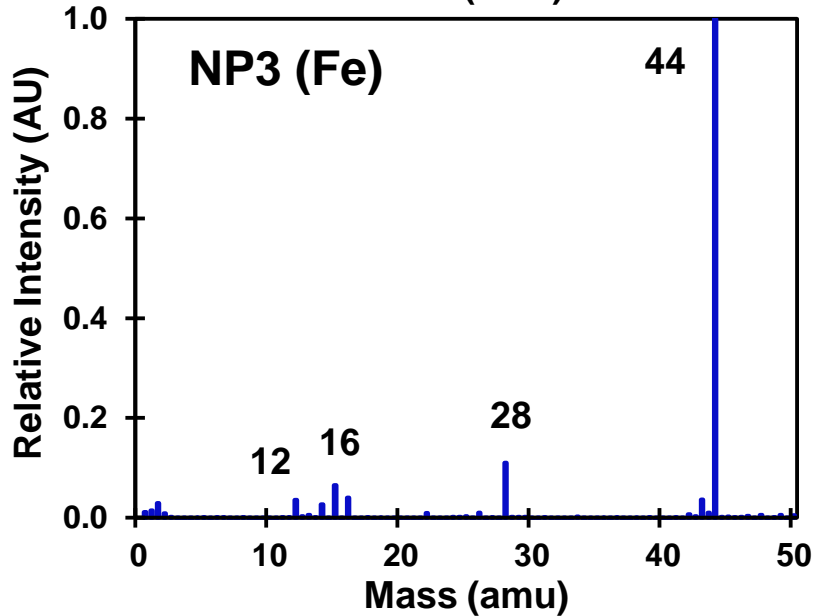
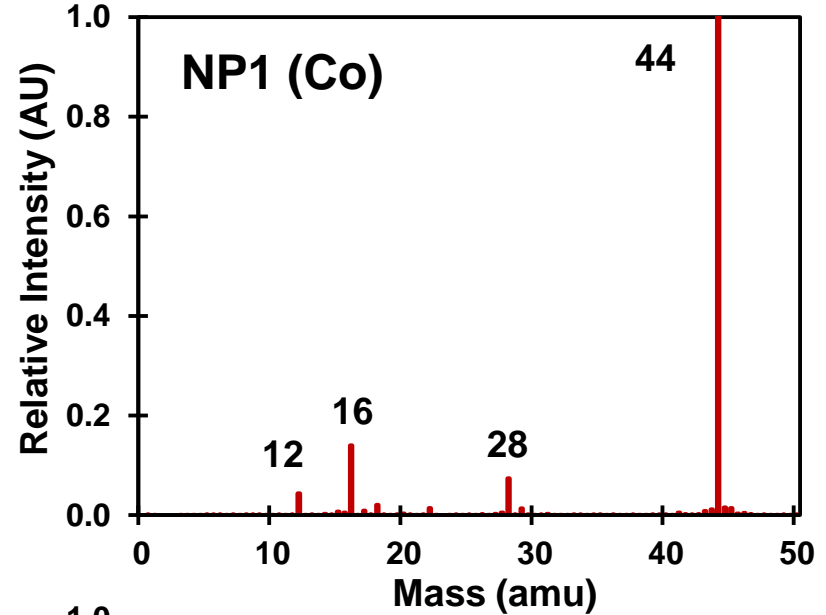
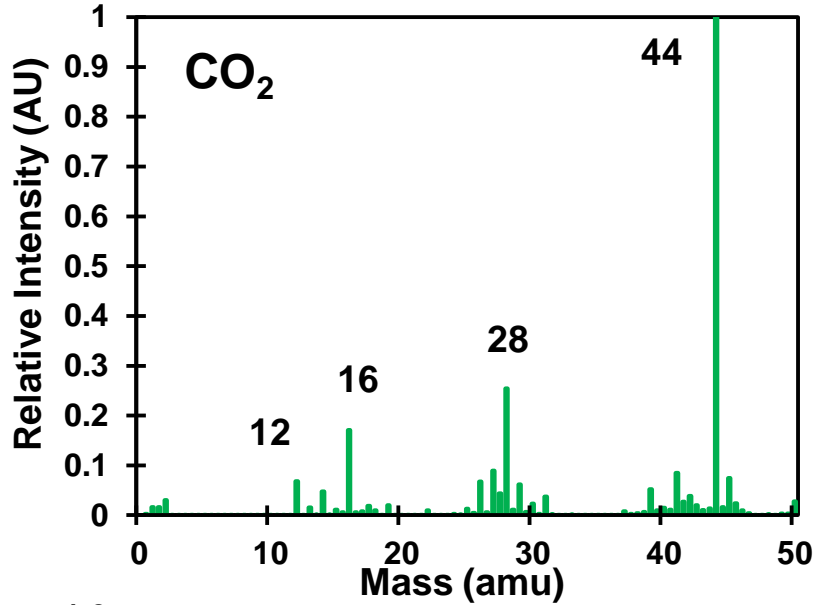


- Upon Exposure to EUV light or electrons CO_2 is generated and outgassed from the resist.
- The photoproduct, Co(II)(bpy)(ox) , is a coordination polymer that polymerizes through bridging oxalate ligands.
- This bridging occurs when one of the oxalate ligands is eliminated as CO_2

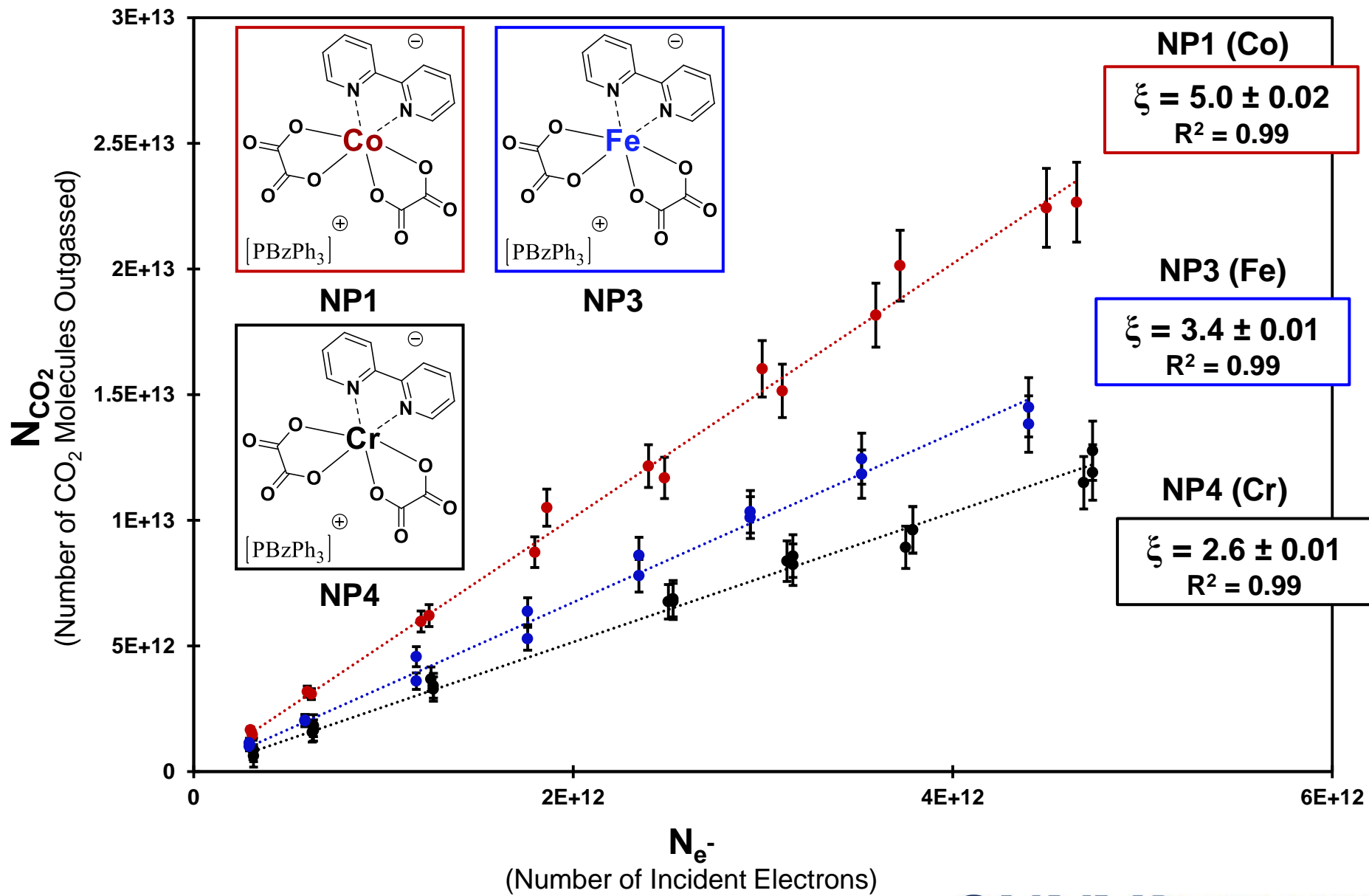
Outgassing Spectra (electrons)



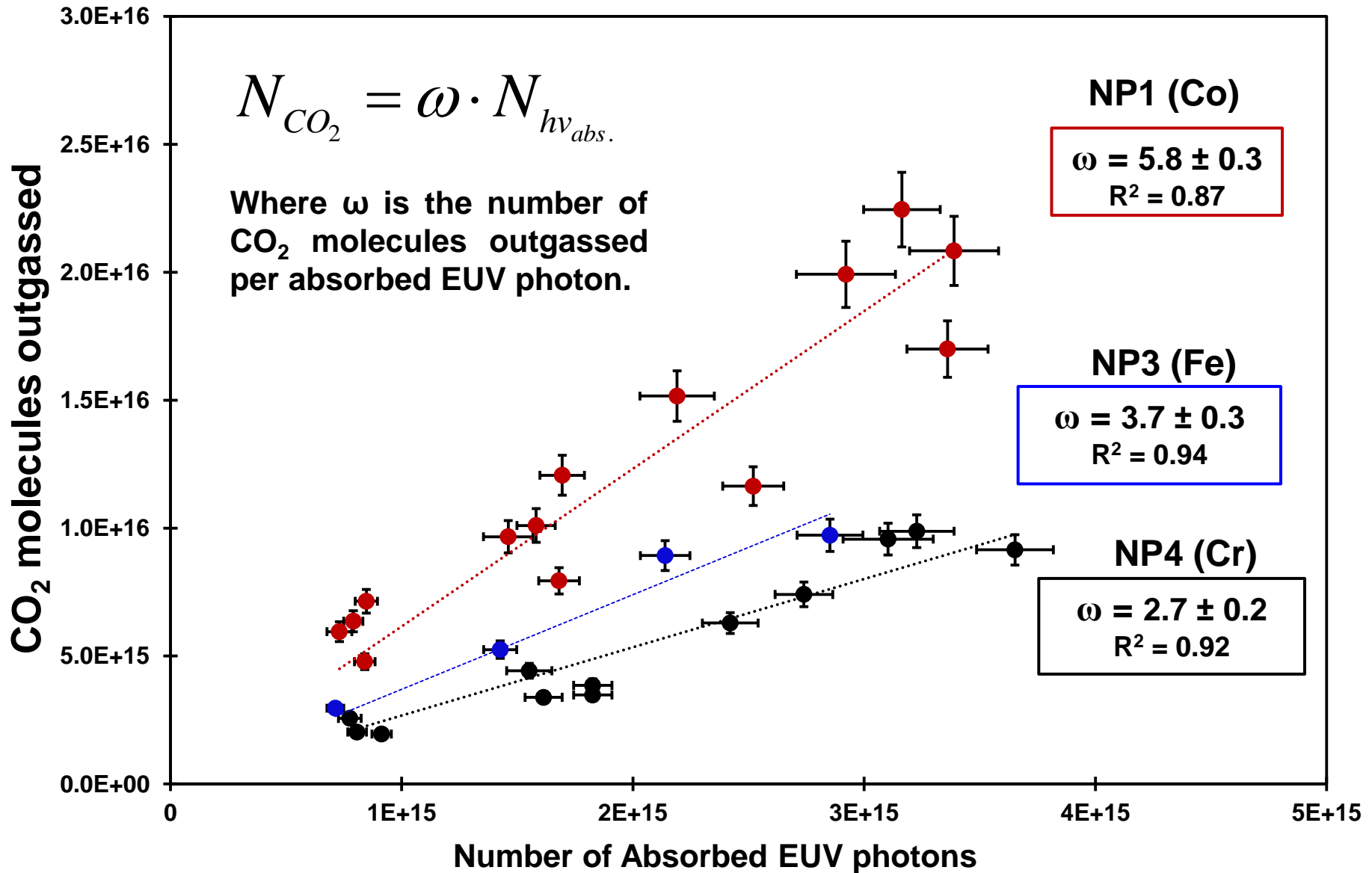
Outgassing Spectra (EUV)



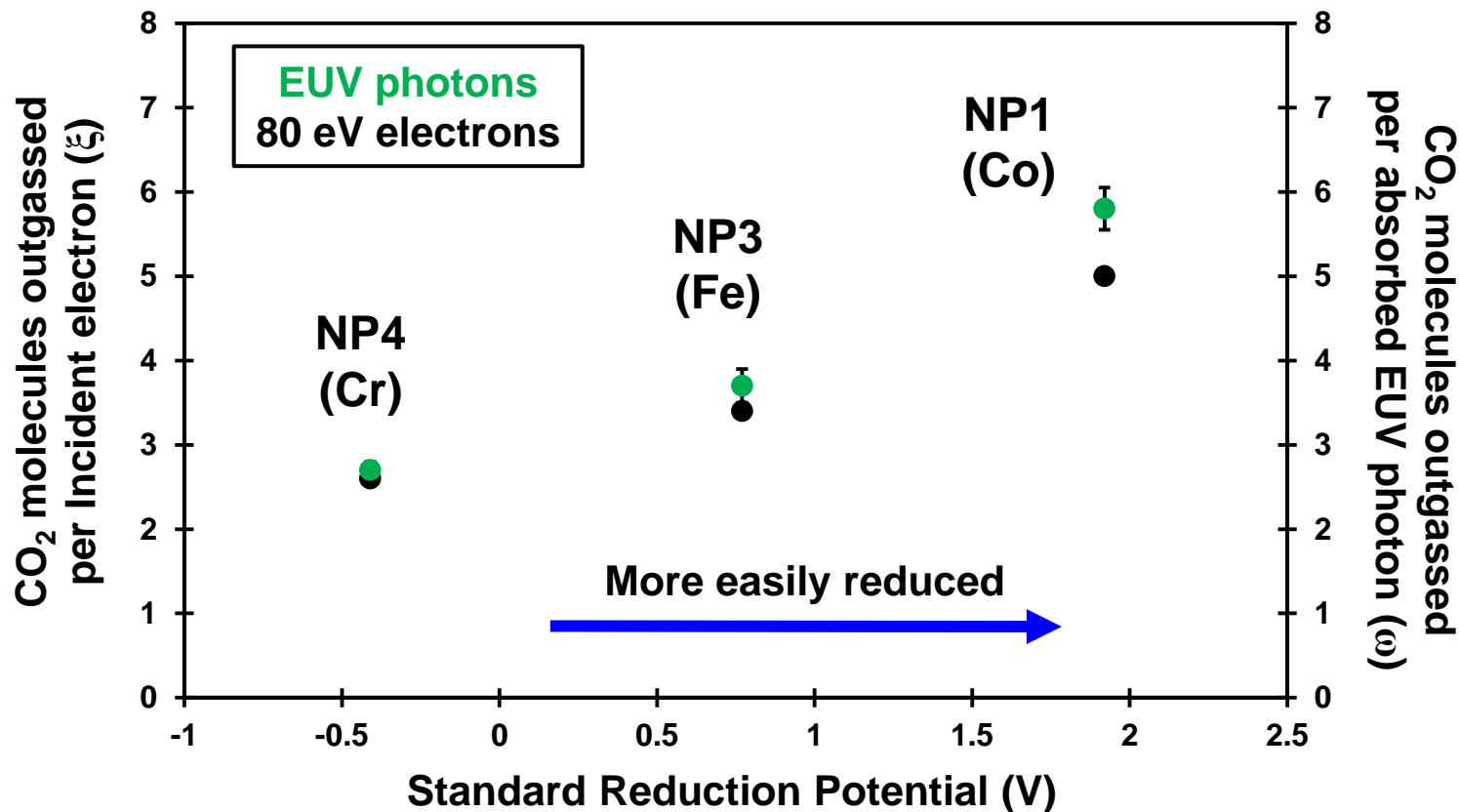
CO₂ Liberated per Incident Electron: 80 eV



CO₂ Liberated per Absorbed EUV Photon

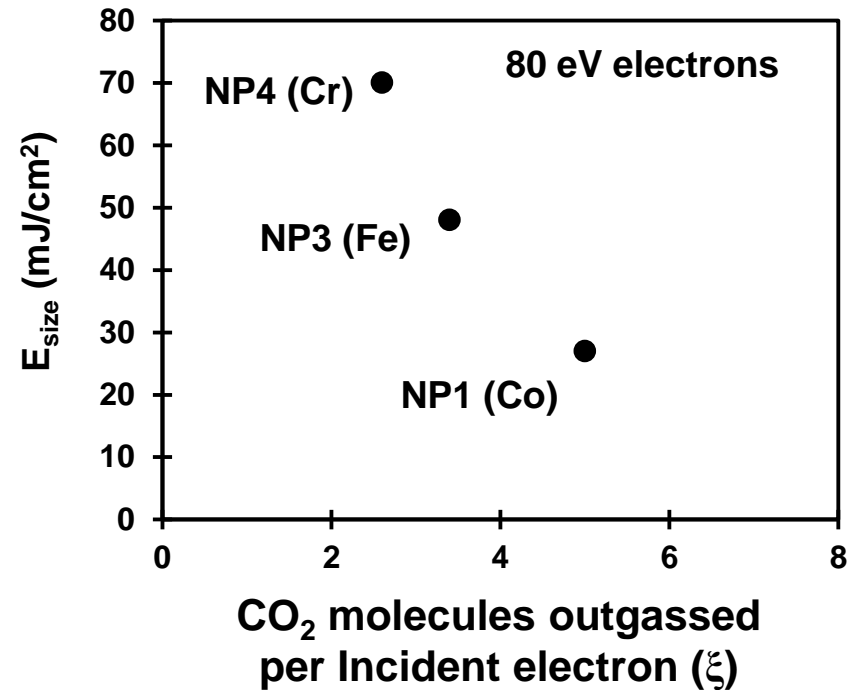
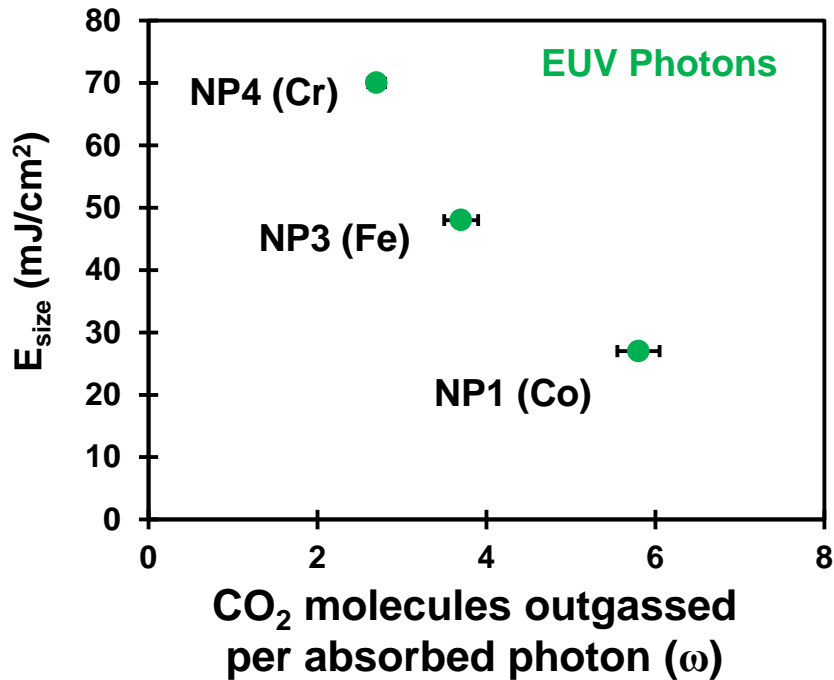


CO₂ Outgassing vs. *Metal Reducibility*



- More easily reduced molecule outgasses more CO₂.
- This could explain the change in E_{size} when varying the central metal.

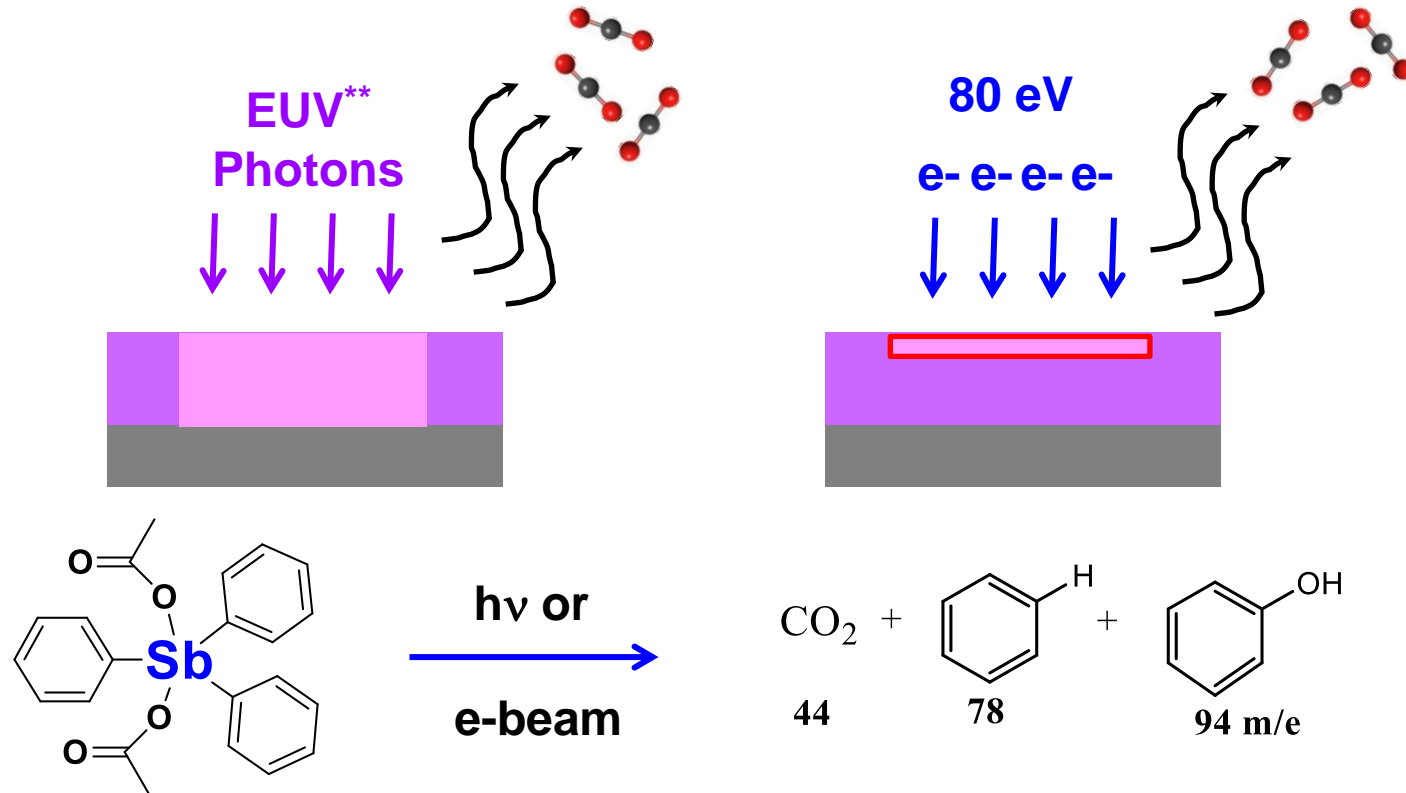
Conclusions



- Between the three photoresists, a small change in EUV absorption does not account for the large change in E_{size} .
- Based upon our understanding of the photo-mechanism increased CO₂ outgassing should improve sensitivity.
- The rate of CO₂ outgassing seems to be correlated to the reducibility of the central metal.

Monday 2:00-2:20 pm,
**“EUV exposure mechanisms of antimony
resists,”**
Presentation by Michael Murphy (10143-3)

III. Mechanistic Studies of Antimony Resists

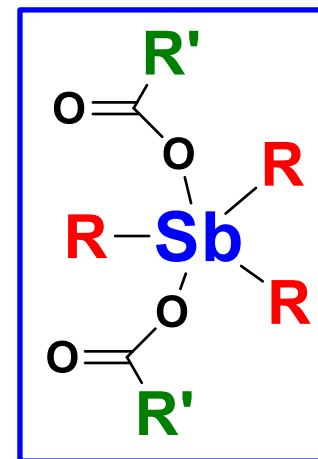
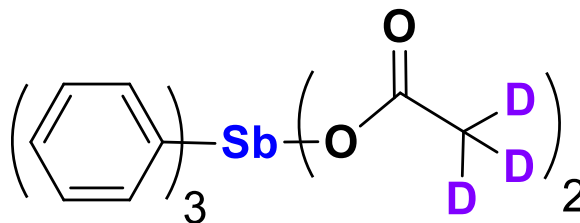
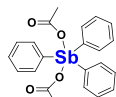
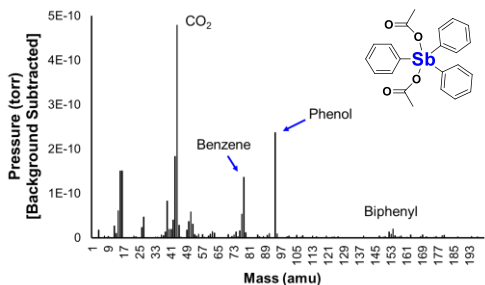


We Exposed Antimony Resists using EUV and E-beam (80 eV) Following Reactions using Mass Spectroscopy.*

*S. Grzeskowiak et al.; J.Vac. Sci.Tech. B 33, 06FH01 (2015).

**EUV generated by Xenon plasma source

III. Mechanistic Studies of Antimony Resists



Study #1:

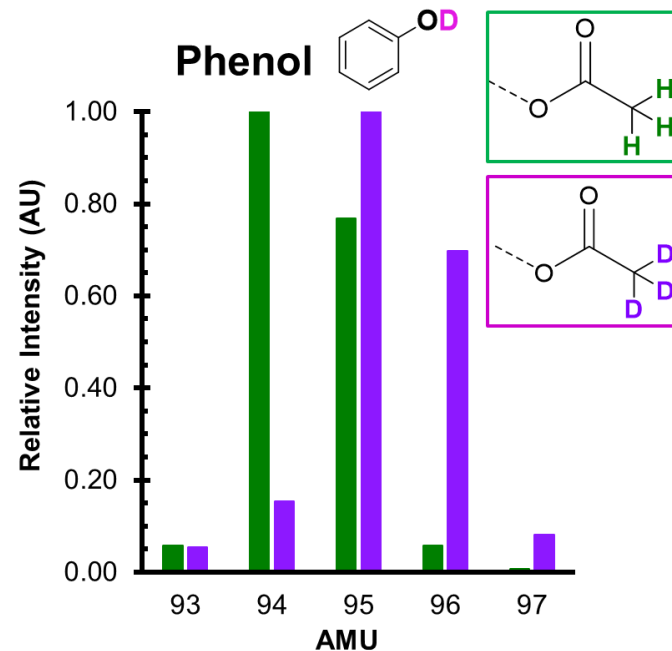
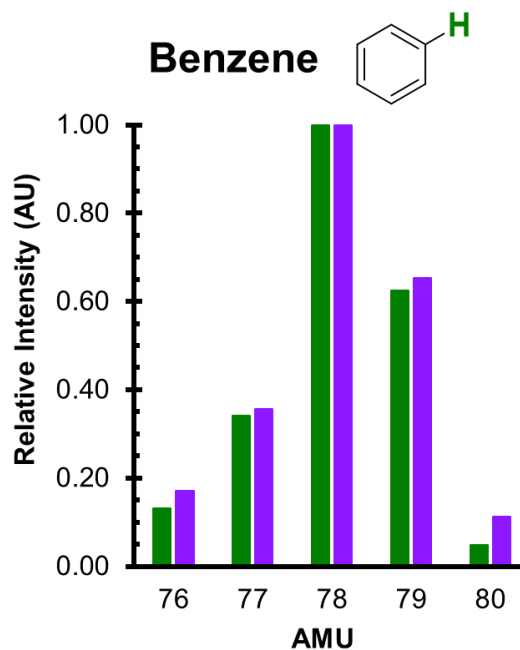
- Reaction monitoring via outgassed products

Study #2:

- Deuterium labeling, site of Hydrogen Abstraction

Each complex abstracts a specific proton with 95% isotopic purity:

- Benzene from phenyl ligand
- Phenol from acetate ligand

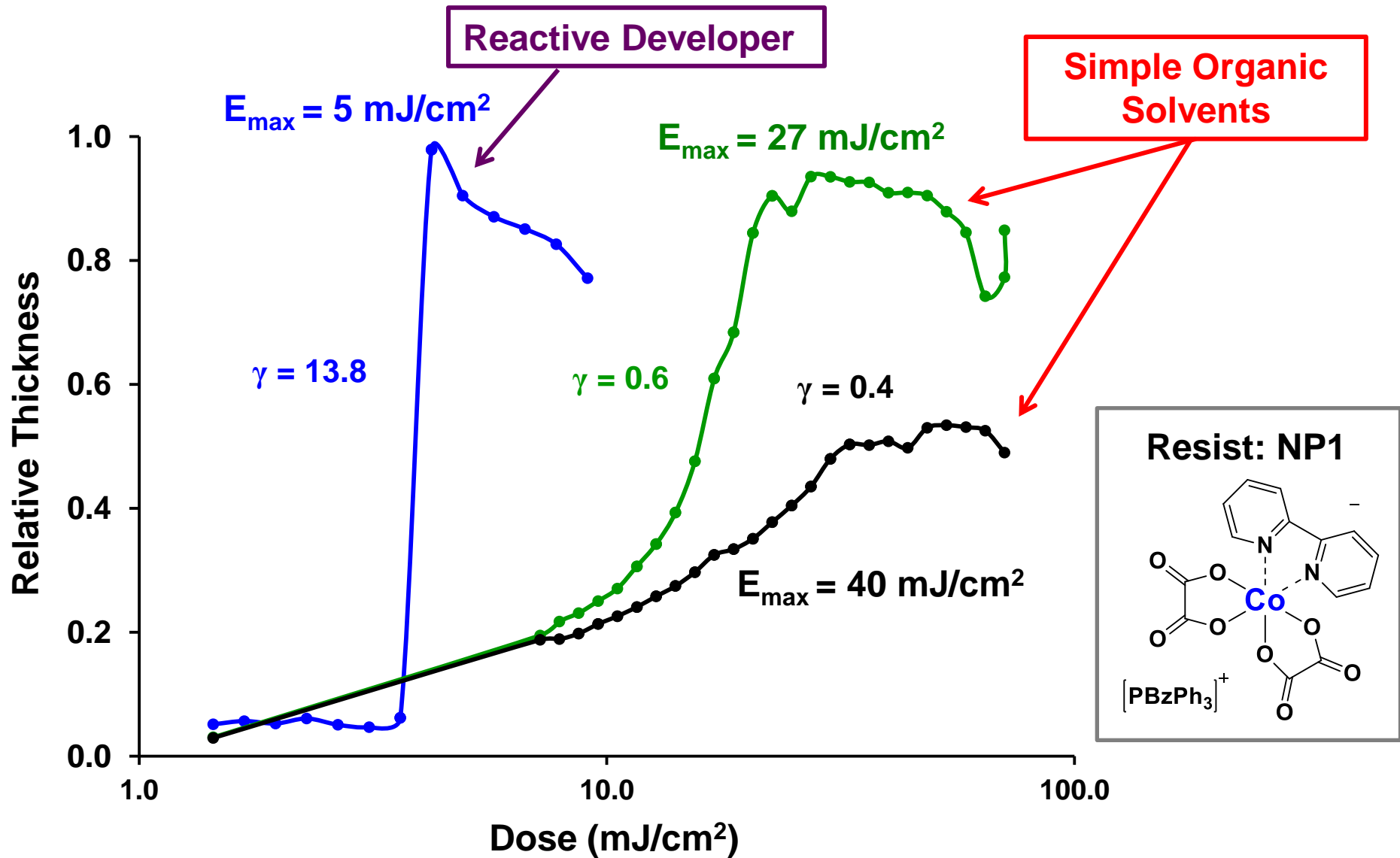


Monday 3:20-3:40 pm,

“Advanced development techniques for metal-based EUV resists,”

Presentation by Jodi Hotalen (10143-5)

Optimizing Development of Metal-Based Resist



Wednesday 10:40-11:00 am,
**“Mechanisms of EUV exposure: electrons,
holes, and molecular interactions,”**
Presentation by Amrit Narasimhan (10143-
28)

IV. PAG Reduction Potentials

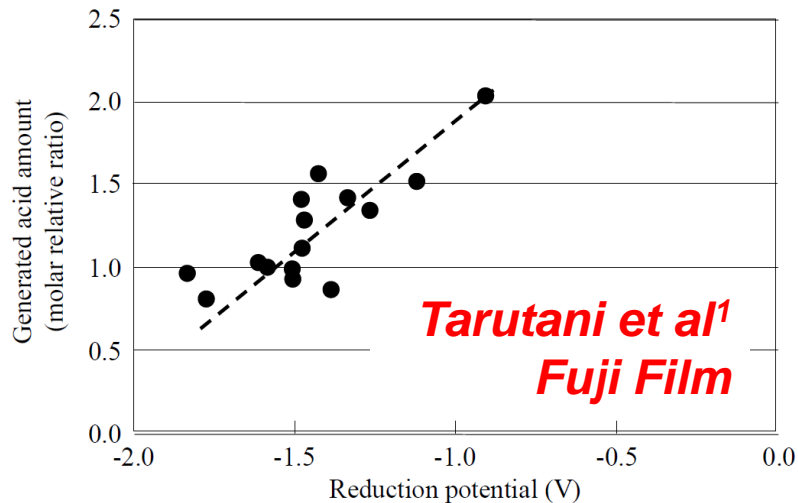
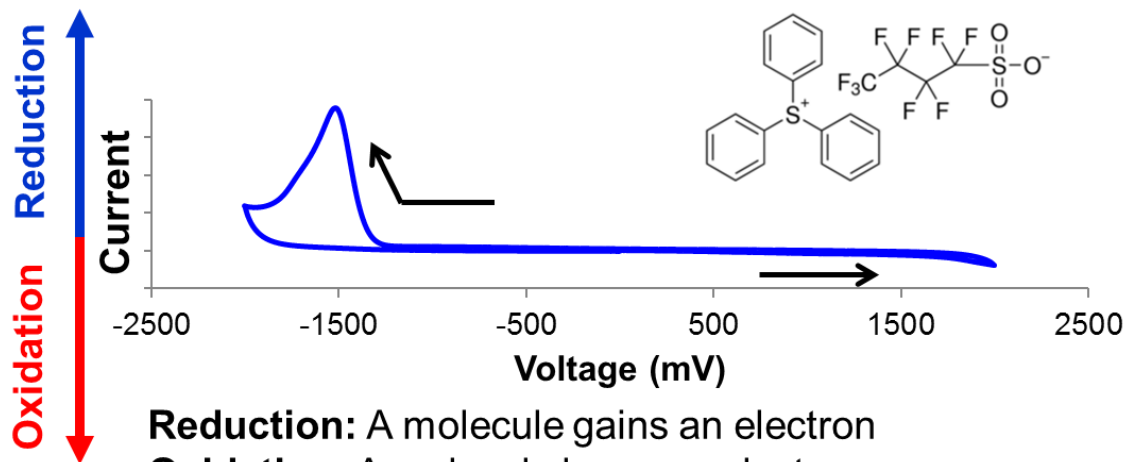
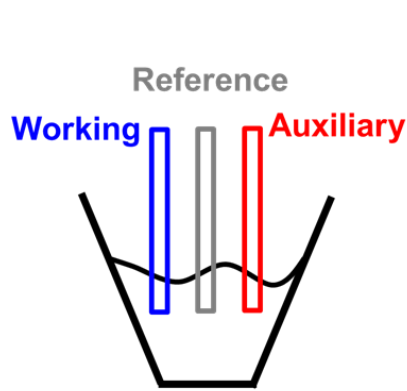
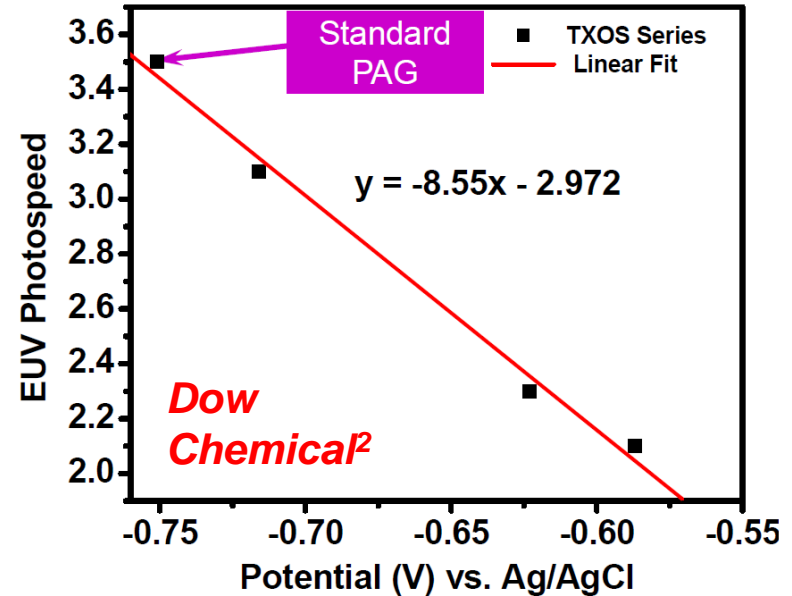


Fig. 4. Relation between reduction potential and acid generation yield.



Reduction: A molecule gains an electron
Oxidation: A molecule loses an electron

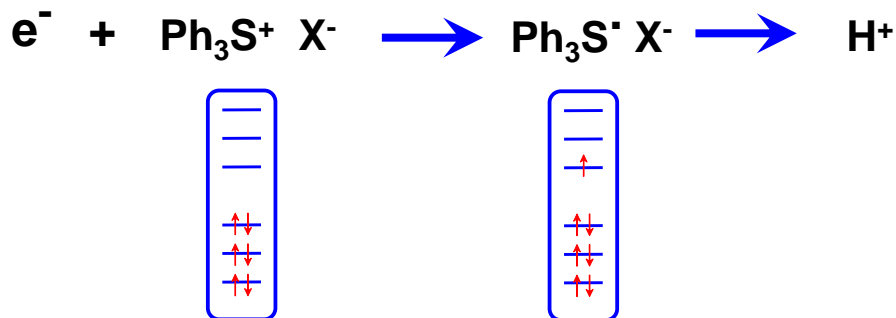
IV. Does $\text{PAG} + \text{e}^- \rightarrow \text{H}^+$?

Electron Trapping

Electron Trapped by PAG:



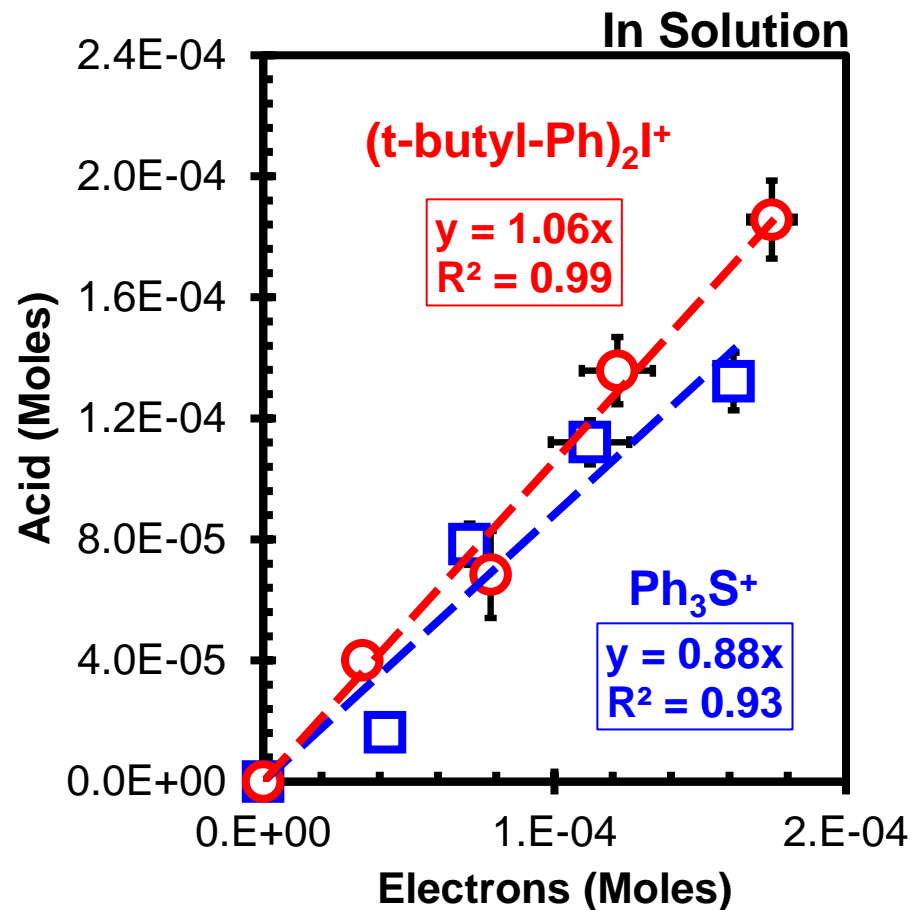
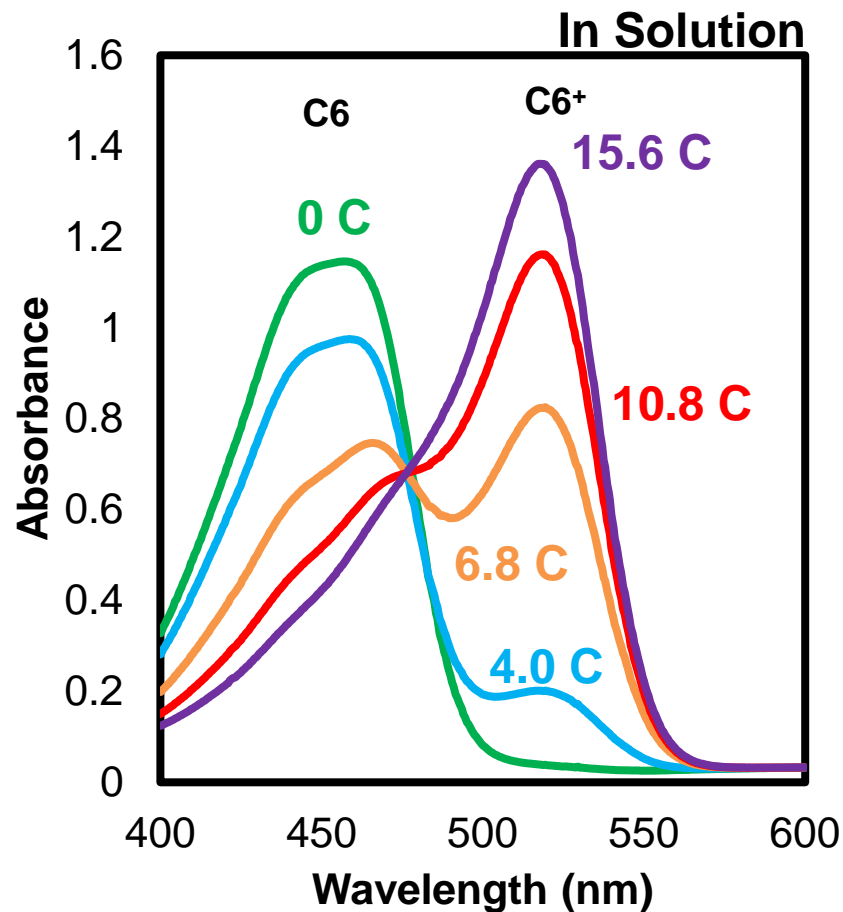
($\Delta E = 2-3 \text{ eV}$)



Bulk Electrolysis with Acid-sensitive dye “indicator”:

- Maintain reduction potential
- Extract aliquots and add to Coumarin 6 indicator solution
- Use standard curve to convert absorbance to $[\text{H}^+]$

IV. Does $\text{PAG} + \text{e}^- \rightarrow \text{H}^+$? Yes!



Bulk electrolysis of PAGs (in Acetonitrile) produces acid